

ABSTRACT

5       A conductive film is formed on a substrate into  
which a MEMS circuit is fabricated, and a film of a  
dielectric A having a low dielectric constant and a film  
of a dielectric B having a high dielectric constant are  
formed on the conductive film, followed by the formation  
of a conductive film over the dielectric films. A  
millimeter wave is guided along the film of the  
10   dielectric B functioning as a dielectric waveguide, and  
is propagated along its length while being reflected by  
the conductors.